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Docket No. 2616 US/RTP/LE  
Express Mail No. EM560888556US

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



In Re the Application of:

Guangcui Xing, Gary E. Miner, David R. Lopes,  
Sita R. Kaluri & Richard N. Tauber

Serial No.

Filed:

For: *Apparatus and Method for Exposing a Substrate to  
Plasma Radicals*

INFORMATION DISCLOSURE STATEMENT

Assistant Commissioner for Patents  
Washington, D.C. 20231

Dear Sir:

Pursuant to Rule 1.97, Applicants desire to make of record the references set forth on the attached Form PTO 1449. Copies of cited reference are submitted herewith.

It is hereby certified that this Information Disclosure Statement is being filed within three months of the filing date of the subject application, therefore no petition or fee is required. However, in the event a petition is needed for consideration of this Information Disclosure Statement, Applicants hereby so petition. Please charge any required fee due to Deposit Account No. 01-1651. A duplicate of this sheet is enclosed for this purpose.

Respectfully submitted,  
APPLIED MATERIALS, INC.

Date: 4/21/95

  
Robert W. Mulcahy, Reg. No. 25,436

Address:  
Legal Affairs Department  
P.O. Box 450A  
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